## Graphene superlattices fabrication by electron beam activated fluorination

## Presenting Author Tianbo Duan<sup>a</sup>

Co-Authors Hu Li<sup>b</sup>, Klaus Leifer<sup>a</sup>

- a. Department of Engineering Sciences, Uppsala University, Uppsala, Sweden
- b. School of Electrical and Electronic Engineering, The University of Manchester, Manchester, United Kingdom

Tianbo.Duan@angstrom.uu.se

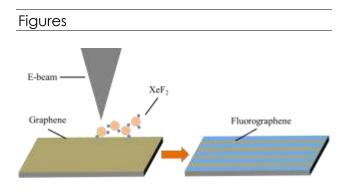
There has been a rising interest in superlattices of graphene based materials with the ultimate goal of modifying the electronic properties artificially by introducing periodic potentials on the graphene surface. Such lateral periodicities can be hBN/graphene induced Morié These systematic patterns. very modifications changes of the cause electronic structure of graphene in the range of meV or smaller. It thus would be interesting to explore modifications of that graphene can induce stronger changes of the electronic structure. Fluorinated graphene is one such candidate. In our work, the graphene superlattice is fabricated by introducing periodic fluorographene pattern on the graphene surface using electron beam activated fluorination (EBAF) technique.

Fluorographene stripe patterns are fabriacted by EBAF in an SEM equipped with XeF<sub>2</sub> gas injector. When large squares of fluorographene are fabricated, they can easily be detected in LOM images. Though, when nanoand microstripes of fluorographene deposited, are the standard height imaging in the AFM cannot be achieved. For visualising the resulting fluorinated stripes on the graphene surface, we refined adhesion mode imaging in the AFM. One such structure is shown in figure 2c. One clearly sees the fluorinated structure with sharp edges. XPS is used to determine the detailed electronic structure of the fluorographene surface and the

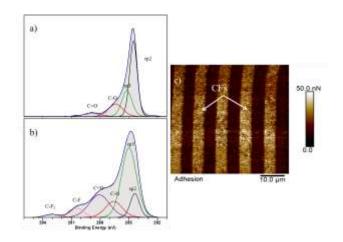
spectrum below shows the formation of C-F and C-F<sub>2</sub> bond. Since the fluorographene stripes are clearly delimited, we explore in this work, to which limit the graphene can be structured. We find that nanostructuring with typical feature sizes in the 100nm range is possible and discuss the limits of this novel structuring process.

References

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**Figure 1:** Schematic illustration of electron beam activated fluorination pattern fabrication



**Figure 2:** XPS spectra of a) pristine graphene; b) Fluorinated graphene; c) Adhesion mapping of fluorographene pattern